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ABSTRACT

WAFER SUPPORT PIN FOR PREVENTING SLIP DISLOCATION DURING ANNEALING OF WATER AND WAFER ANNEALING METHOD USING THE SAME

A wafer support pin has a front end contacted with a wafer such that the front end is flat or rounded. Thus, gravitational stress is minimized during annealing the wafer, thereby minimizing slip dislocation. This wafer support pin is suitably used for annealing of a wafer, particularly high temperature rapid thermal annealing of a large-diameter wafer.

FIG. 8